FIG.1

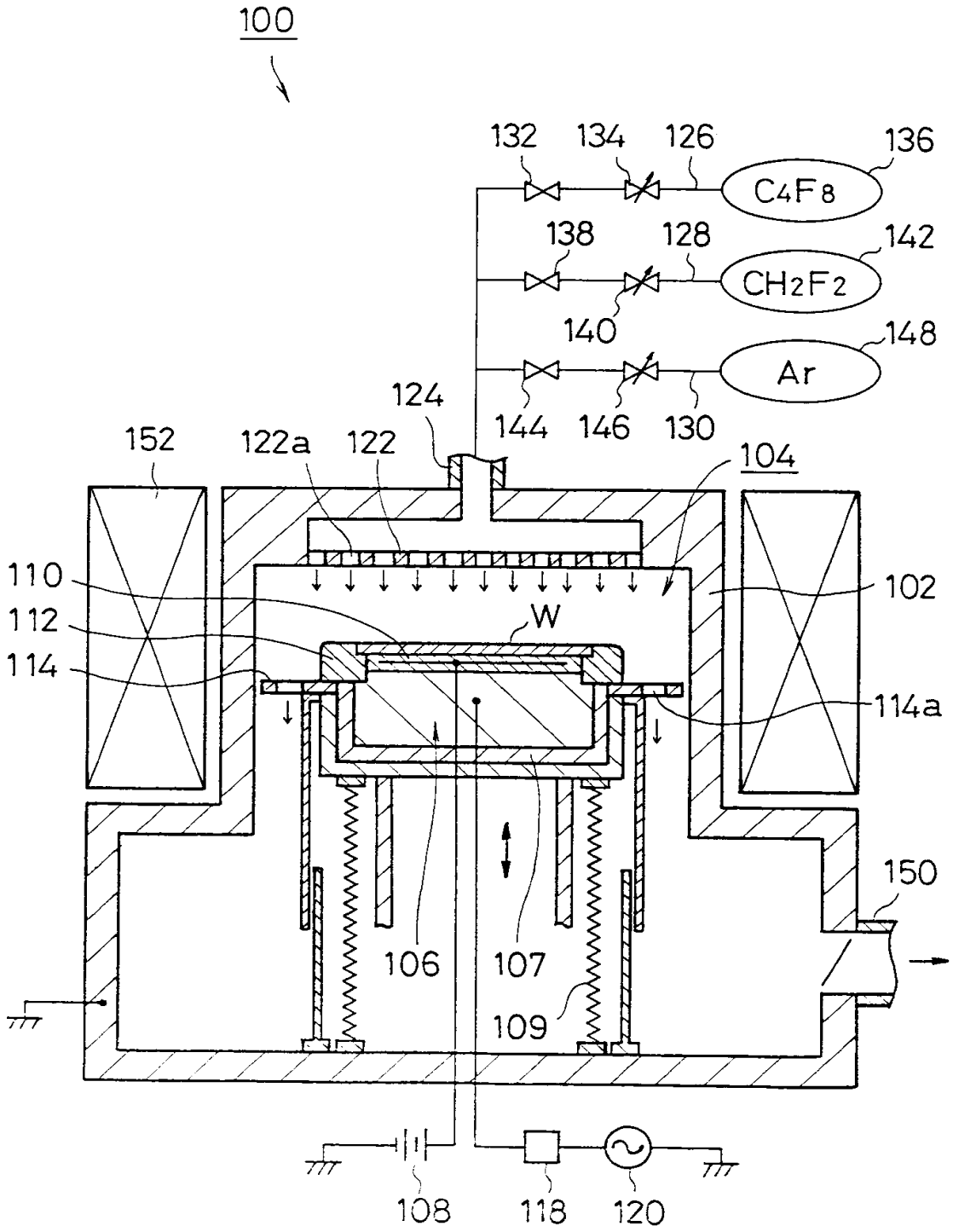

100
132
134
126
136
C4F8
138
128
142
CH2F2
140
148
Ar
144
146
130
124
152
122a
122
104
110
112
114
102
W
114a
150
106
107
109
108
118
120

FIG.2

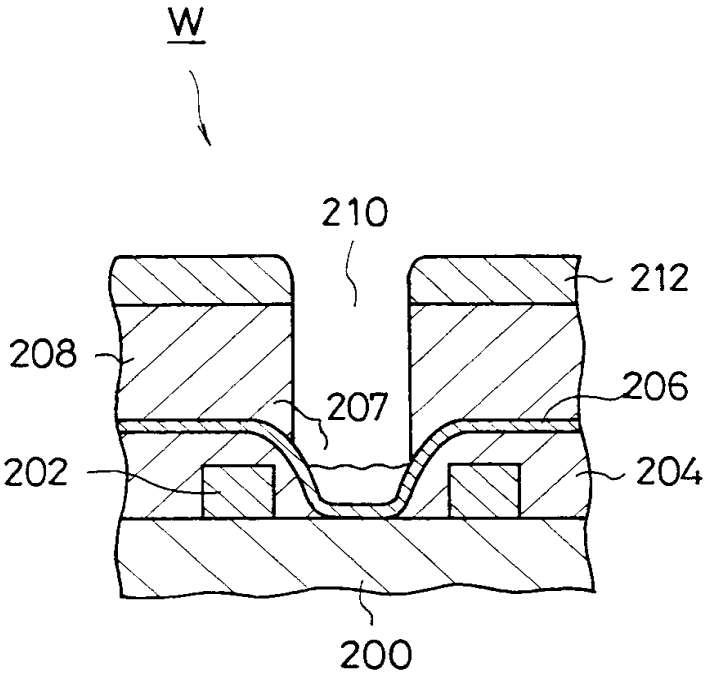
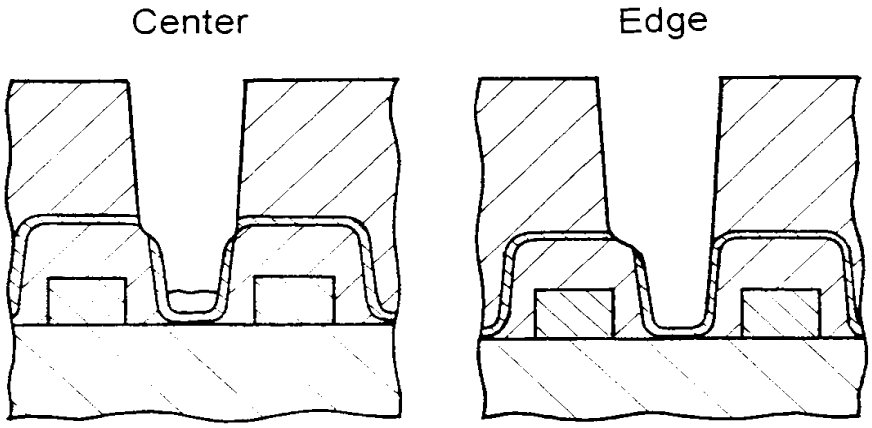
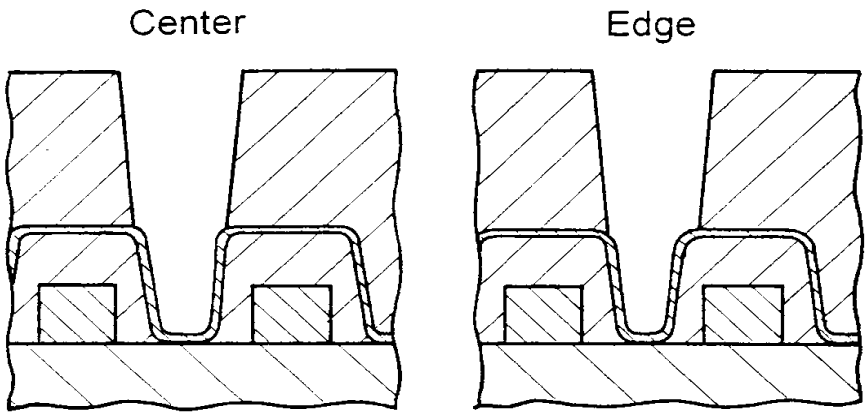


FIG.3



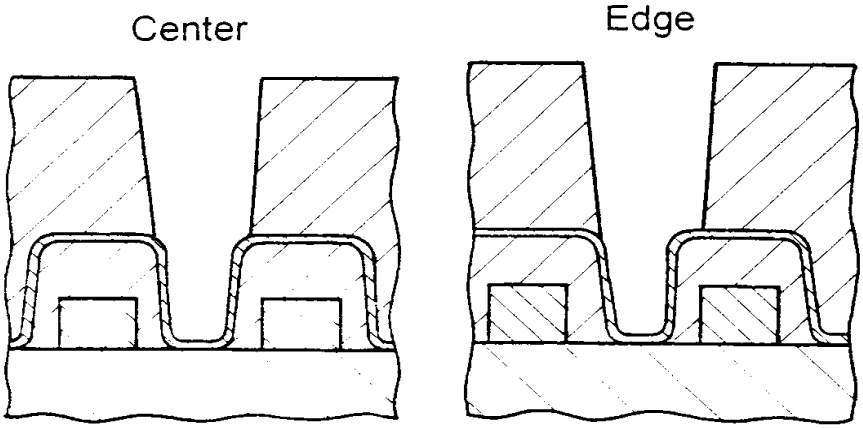
Implementation Example 1

FIG.4



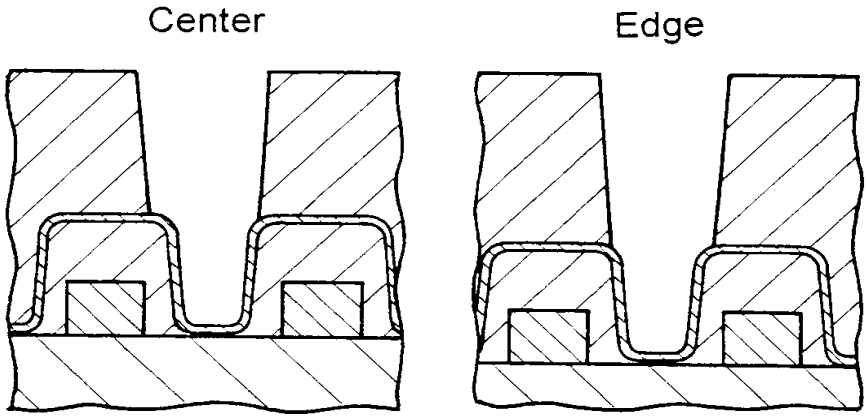
Implementation Example 2

FIG.5



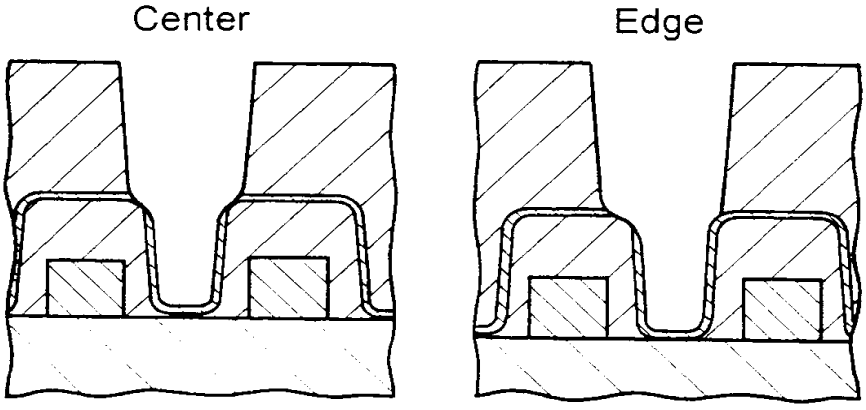
Implementation Example 3

FIG.6



Implementation Example 4

FIG.7



Implementation Example 5

FIG.8

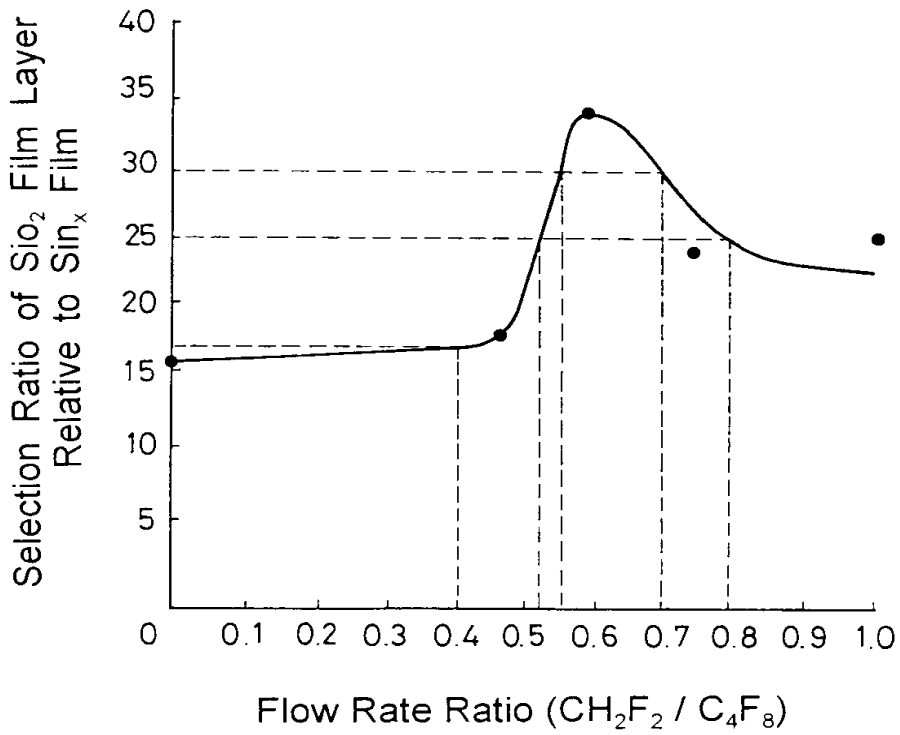
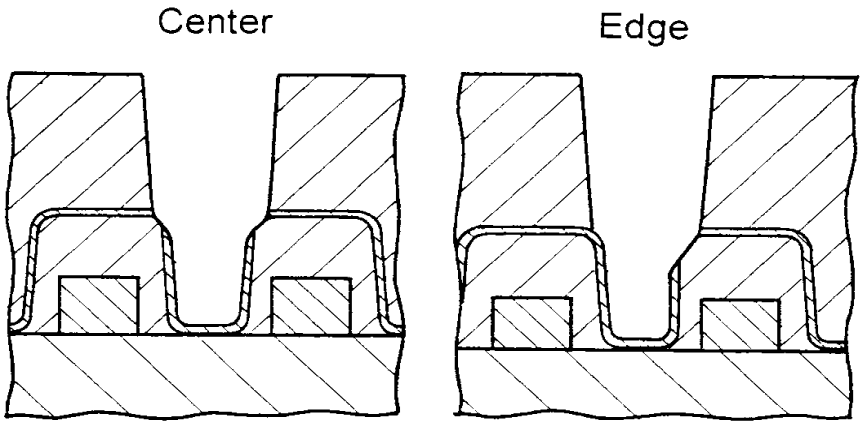
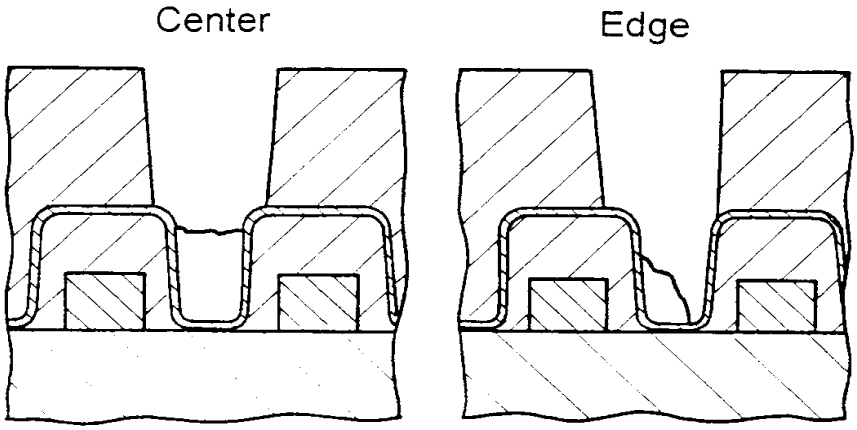

Selection Ratio of SiO_2 Film Layer Relative to SiN_x Film
40
35
30
25
20
15
10
5
0
0.1
0.2
0.3
0.4
0.5
0.6
0.7
0.8
0.9
1.0
Flow Rate Ratio (CH_2F_2 / C_4F_8)

FIG.9



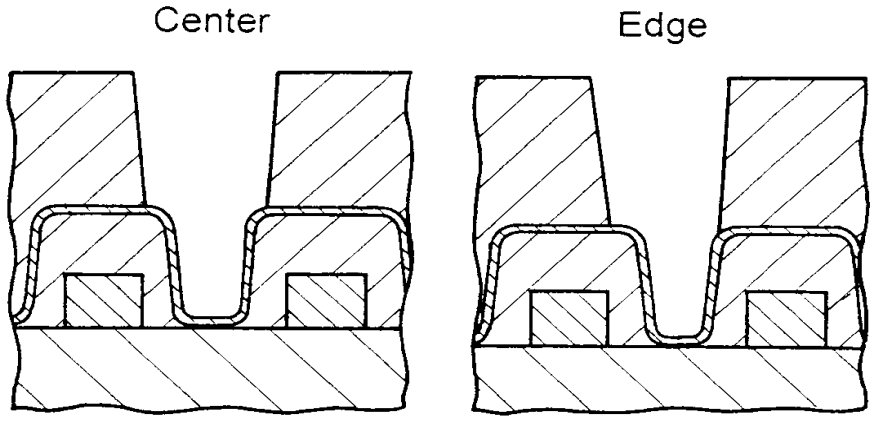
Implementation Example 6

FIG.10



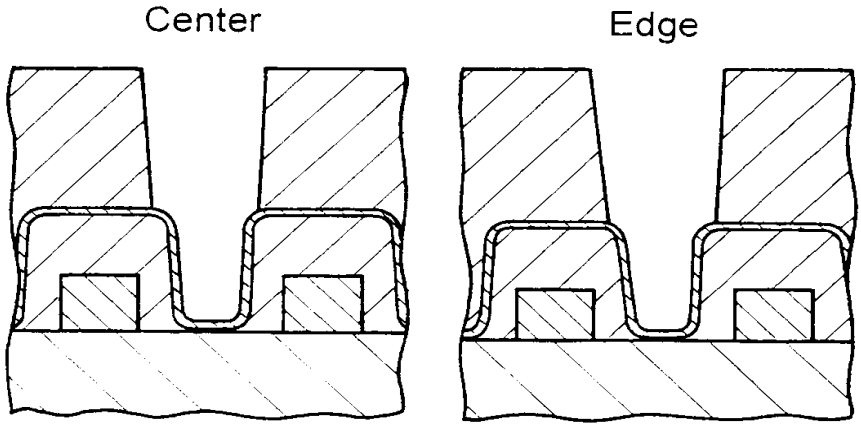
Implementation Example 7

FIG.11



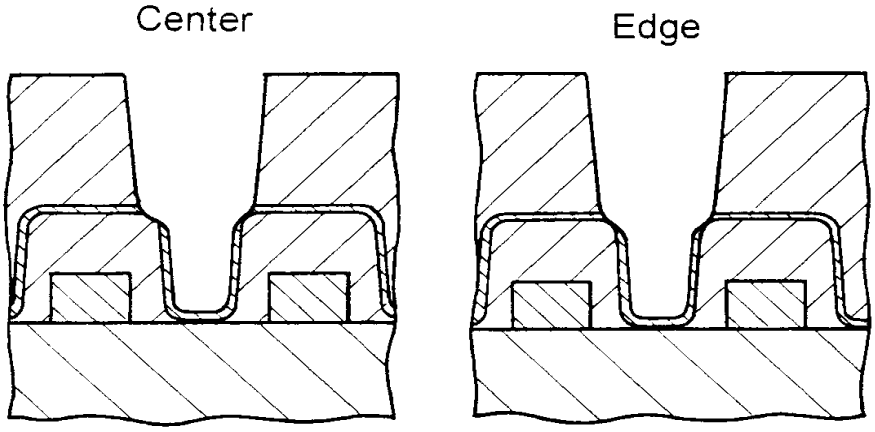
Implementation Example 8

FIG.12



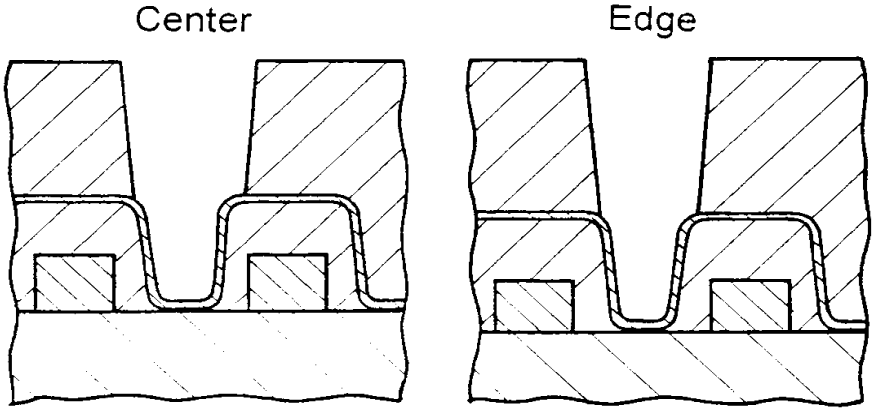
Implementation Example 9

FIG.13



Implementation Example 10

FIG.14



Implementation Example 11

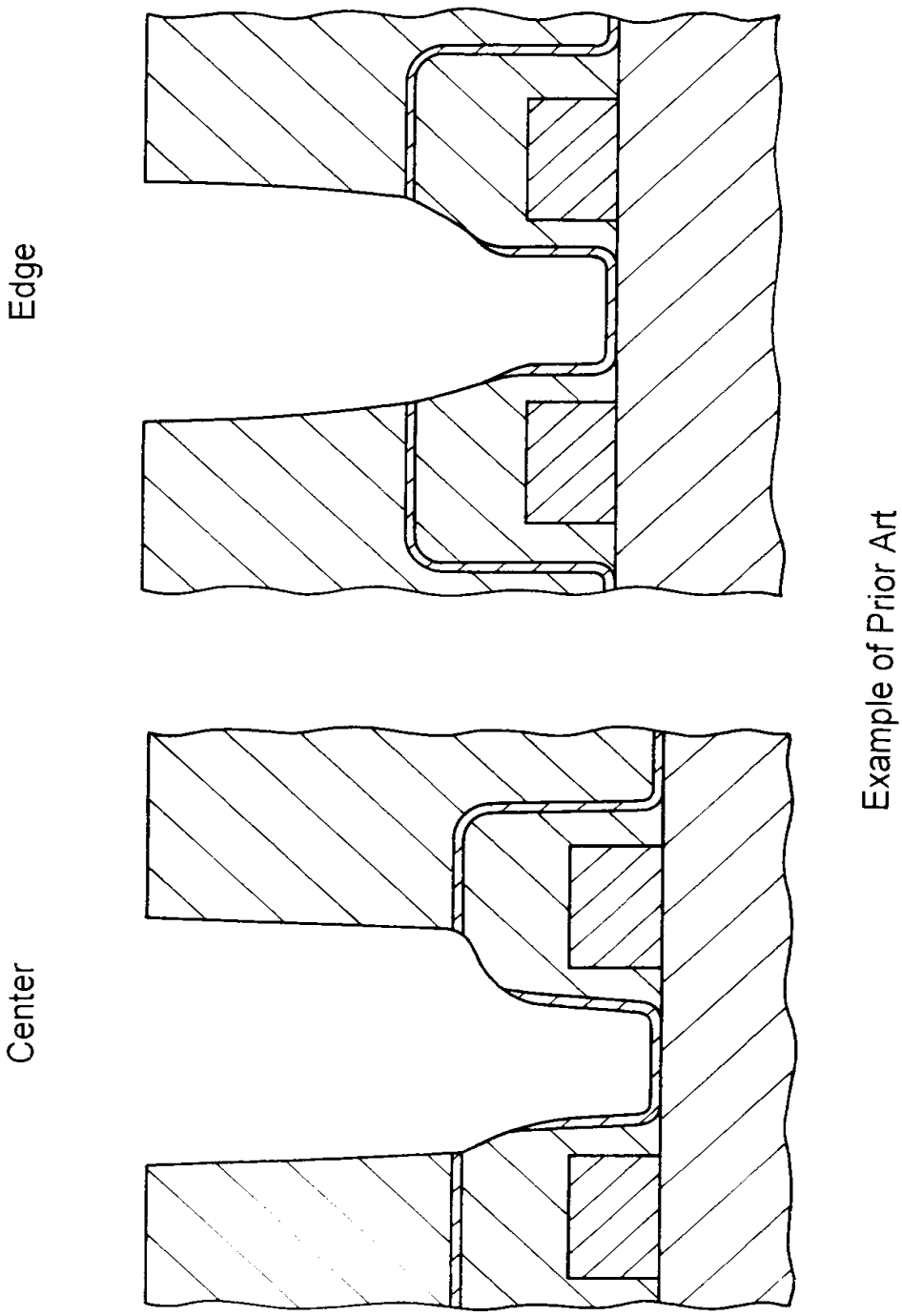



FIG.15